

Amendments to the Claims:

This listing of the claims will replace all prior versions, and listings, of the claims in the application:

1. - 10. (Cancelled).

11. (Currently amended) An apparatus for positioning and bonding probes to a substrate of a probe card, comprising:

a stage unit on a working table, the stage unit being movable in three dimensions and supporting the substrate;

a microscope coupled to a first guide member positioned at a first portion of the working table and placed above the stage unit;

a probe fixing unit mounting on a supporting member in such a configuration that the probe fixing unit moves on the supporting member vertically to the working table, an end portion of the probe fixing unit to which a probe is fixed being interposed between the microscope and the stage unit so that the probe makes contact with the substrate at a connected portion thereof; and

a light source unit movably coupled to a second guide member positioned at a second portion of the working table, a laser being emitted to the connection portion of the substrate from the light source unit, to thereby bonding the probe to the substrate at the connection portion of the substrate,

wherein the probe fixing unit includes:

a bracket moveably secured to the supporting member and including a pair of plates and a shaft interposed between the plates;

a pincette moveably secured to the bracket and including a head portion secured to the bracket and a gripping portion opposite to the head portion to which the probe is fixed, the head portion of the pincette being secured to the shaft in a space between the plates; and

a controller for controlling an open angle of the pincette, the controller positioned at a side of the pincette and applying a pressure to the pincette.

12. (Previously Presented) The apparatus of claim 11, wherein the stage unit includes an x-axis moving stage, a y-axis moving stage and a z-axis moving stage moving in an x-axis direction, a y-axis direction and a z-axis direction in a Cartesian coordinate system and a rotating stage rotated about the z-axis direction, and the x-axis moving stage, the y-axis moving stage, the z-axis moving stage and the rotating stage are vertically disposed one and another from bottom to top.

13. (Previously Presented) The apparatus of claim 12, wherein the substrate is positioned on the stage unit by three-dimensional movement of the stage unit in such a configuration that the connected portion of the substrate corresponds to the probe gripped to the end portion of the probe fixing unit, and the position of the substrate is verified by the microscope.

14. (Currently amended) The apparatus of claim 11, wherein the probe includes a supporting beam and a probe tip positioned on a first end portion of the supporting beam, and the supporting beam of the probe is bonded to the connected portion of the substrate and the probe tip faces outwards.

15. (Previously Presented) The apparatus of claim 14, wherein the probe fixing unit moves vertically on the supporting member upward without movement of the stage unit, so that another probe is gripped by the probe fixing unit without change of the position of the substrate on the stage unit.

16. (Previously Presented) The apparatus of claim 11, wherein the first guide member includes a first supporting member fixed to the first portion of the working table and a first arranging member extending from an end portion of the first supporting member in a first direction and the second guide member includes a second supporting member fixed to the second portion of the working table and a second arranging member extending from an end portion of the second arranging member in a second direction opposite to the first direction, and the microscope is coupled to the first arranging member over the stage unit and the light source unit

is mounted onto the second arranging member movably along the second arranging member close to or away from the microscope unit.

17. (Currently amended) The apparatus of claim 16, wherein the first and second guide members are positioned at both sides of the stage unit on the working table and the probe fixing unit supporting member is positioned on a backside of the stage unit on the working table.

18. - 19. (Cancelled).

20. (Currently amended) The apparatus of claim 119, wherein the gripping portion of the pincette includes a pair of grooves facing each other to which the probe is gripped.

21. (Cancelled)

22. (Currently amended) The apparatus of claim 211, wherein the bracket further includes an adjusting member installed to the shaft and the head portion of the pincette is secured to the adjusting member in such a configuration that the pincette linearly moves in accordance with a rotation of the adjusting member about the shaft.

23. (Currently amended) The apparatus of claim 119, wherein the controller includes an open angle controller positioned at a first side of the bracket and a reciprocating mover positioned at a second side opposite to first side of the bracket the bracket, so that the opening angle of the gripping portion of the pincette is controlled by the pressure applied by the controller.

24. (Previously Presented) The apparatus of claim 23, wherein the reciprocating mover applies the pressure to the gripping portion of the pincette from the second side of the bracket while the open angle controller supports the gripping portion of the pincette at the first side of the bracket.

25. (Previously Presented) The apparatus of claim 24, wherein the reciprocating mover applies the pressure to the gripping portion of the pincette by a piston operated by an air compressor or an electrical solenoid.